



PATENT

**IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE**

Applicant: Young-Soo Kim)

Serial No.: 10/615,038)

Filed: July 8, 2003)

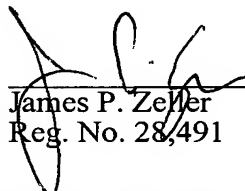
For: ATOMIC LAYER)
DEPOSITION OF TITANIUM)
NITRIDE USING BATCH TYPE)
CHAMBER AND METHOD FOR)
FABRICATING CAPACITOR BY)
USING THE SAME)

Group Art Unit: 2891)

Examiner: Bradley Smith)

I hereby certify that this paper (or fee) is being
deposited with the United States Postal
Service, first class postage prepaid, addressed
to: Commissioner for Patents, P.O. Box 1450,
Alexandria, VA 22313-1450

October 12, 2005


James P. Zeller
Reg. No. 28,491

AMENDMENT AFTER ALLOWANCE UNDER 37 C.F.R. § 1.312

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please amend this application as follows:

the amendments to the specification section begins on page 2 of this paper;

the remarks section begins on page 3 of this paper.